

Posters

MNE 2006

Poster Contributions

NAME	TITLE	PROGR. REF.	Location
Micro- and Nano- Systems for Biology			
Alicia Johansson	Piezoresistive SU-8 cantilever floor for investigation of cell-substrate interactions and biomechanics	P-BIO01	Agora
Reo Kometani	Methods to control microtubules' movement for development of dynein-based bio nano-devices	P-BIO02	Agora
Cecile Crozatier	Microfluidic modulus for convenient cell culture and screening experiments	P-BIO03	Agora
Janette Lilian Maria Schulze	Micro SU-8 Chamber for Real-Time PCR of Salmonella spp. DNA	P-BIO04	Agora
Yong Chen	Fast temperature control using an integrated cooling system for on-chip quantitative PCR.	P-BIO05	Agora
Tien-Li Chang	Effect of Different Gold Nanoparticle Sizes to Build an Electrical Detection DNA between Nanogap Electrodes	P-BIO06	Agora
Daniel Ramos	Optical actuation of microcantilevers in liquids	P-BIO07	Agora
Enric Claverol-Tinturé	Star-shaped Polymer-on-Multielectrode (PoM) arrays for interfacing with neurons	P-BIO08	Agora
Dong-Woo Cho	3D scaffold fabrication with PPF/DEF using micro-stereolithography	P-BIO09	Agora
Andreas Heeren	Manipulation of Micro- and Nanoparticles by Electro-Osmosis and Dielectrophoresis	P-BIO10	Agora
Christophe Peroz	Laser-on-chip using second order distributed Bragg Reflectors fabricated by soft UV nanoimprint lithography	P-BIO11	Agora
Mike Geneviève	Bio-functionalization of gold nano-particles and their spectral properties	P-BIO12	Agora
Ernest Mendoza	Fabrication of Microelectrodes based on carbon nanotubes for biosensing applications	P-BIO13	Agora
Guillaume Mernier	On-Chip in situ Release of Neurotransmitter for Neuronal Stimulation	P-BIO14	Agora
Dong-Weon Lee	Fabrication and Evaluation of a novel protein sensor based on the Lorentz force	P-BIO15	Agora
Jian Shi	Fabrication and Surface Functionalization of High Aspect Ratio Plastic Nanostructures	P-BIO16	Port Vell
Marco Matteucci	Micro-mechanical stress for cancer metastasis studies	P-BIO17	Port Vell
Ana Ruiz	Direct printing of proteins to fabricate nano/micro-engineered surfaces for cell culturing	P-BIO18	Port Vell
Marco Matteucci	Micropatterned Dry Electrodes for Brain-Computer Interface	P-BIO19	Port Vell
Krzysztof Malecki	Polymer-Glass Fluidic Microdevice for Single Cell Photodynamic Therapy Evaluation	P-BIO20	Port Vell
Duc Duong-Hong	Dissipative Particle Dynamics for Simulating Nanofluidic Biomolecules Filters	P-BIO21	Port Vell
Ilona Grabowska	Microfluidic system with electrochemical and optical detection	P-BIO22	Port Vell
Irina Kleps	Development of the micro- and nanoelectrodes for cells investigation	P-BIO23	Port Vell
Johann Mertens	Profiling of Cantilever Arrays for Sensing Applications	P-BIO24	Port Vell
Petros Argyrakis	Fabrication and characterization of a biomorphic wind sensor for integration with a neuron chip	P-BIO25	Port Vell
Chris Mills	Micro- and Nanostructured Polymer Surfaces for Biomedical Applications	P-BIO26	Port Vell
Fu-Hsiang Ko	Selective Bottom-up Assembly of Active Enzyme onto the Silicon-based Surfaces	P-BIO27	Port Vell
Marco Matteucci	A Compact and Disposable Transdermal Drug Delivery System	P-BIO28	Port Vell
Frederic Bretagnol	Fabrication of nano patterned surfaces by electron beam lithography and plasma processes	P-BIO29	Port Vell
Rafal Wierzbicki	Low-voltage driven electrostatic microgripper for biotechnology	P-BIO30	Port Vell
Jérôme Chalmeau	Elaboration of Micro-domains of supported bilayers using Microcontact printing	P-BIO31	Port Vell
Herbert Schuck	Rapid prototyping of 3D micro- nanostructures to explore cell behaviour	P-BIO32	Port Vell
Yong Chen	Microfluidic device for protein crystallization under controlled humidity	P-BIO33	Port Vell
Liviu Nicu	Molecularly Imprinted Polymer-based immunoassay using resonant piezoelectric membranes with integrated actuation and detection scheme	P-BIO34	Port Vell
Dong-Woo Cho	Development of bone scaffold using HA nano powder and MSTL technology	P-BIO35	Port Vell
Jongheop Yi	In-situ observation of superoxide dismutase aggregates behaviour on the patterned surface via a scanning probe microscopy	P-BIO36	Port Vell
Ya-Wei Lee	NARMAX Models for Droplet Behaviors in Microjet Experimental Study	P-BIO37	Port Vell
Mauricio Moreno	Optical sub-micron grating-waveguides for biosensor applications	P-BIO38	Port Vell
Process Diagnosis and Control			
Neus Sabate	FIB-based technique for the measurement of local residual stresses on thin films	P-DIAG1	Agora
Faisal Mohd-Yasin	Low Frequency Noise Measurement and Analysis of Capacitive Micro-Accelerometers	P-DIAG2	Agora
Masashi Kuwahara	Measurement of the thermal conductivity of nano-meter scale thin films by thermoreflectance phenomenon	P-DIAG3	Agora
Uwe Huebner	A lateral nanoscale linewidth/pitch standard for every day calibration of high-resolution microscopy techniques	P-DIAG4	Agora
David Mendels	Design and Modelling of a Load Cell for micro-Newton Force Measurement	P-DIAG5	Agora
Wen-Fa Wu	Effect of capping layers on the electrical characteristics of nickel silicided junctions	P-DIAG6	Agora
Shaojun Fu	Study on the Surface Roughness of Substrate with Multi-Fractal Spectrum	P-DIAG7	Agora
Marco Cucinelli	Mask Aligner Lithography: Pushing the Limits	P-DIAG8	Agora
Electron and Ion Beam Lithography			
Martijn Van Bruggen	Electrostatic blanker array for the fabrication of sub-10 nm structures with multi-electron-beam induced deposition	P-EIBL01	Agora
Rafael Aldana	Miniature traveling wave deflection for electron beam analog to digital conversion	P-EIBL02	Agora
Susanne Beuer	Accurate parameter extraction for the simulation of direct structuring by ion beams	P-EIBL03	Agora
Peter Hudek	Fogging Effect Correction Method in High-Resolution Electron Beam Lithography	P-EIBL04	Agora
Sergey Zaitsev	Dose deposited during e-beam exposure fluctuations simulation	P-EIBL05	Agora
Dong-Woo Cho	Design & Measurement of Nano-patterns for FIB Reliability Assessment	P-EIBL06	Agora
A.E. GRIGORESCU	Sub-10 nm linewidth in HSQ, using Electron Beam Lithography	P-EIBL07	Agora
Hisatake Sano	Analysis of pattern-dependent image placement of single-membrane stencil masks for e-beam lithography	P-EIBL08	Agora
Eva Terrado	Controlled growth of carbon nanotubes on sites predefined by focused ion beam lithography	P-EIBL09	Agora
Wuxia Li	Fabrication of micro/nano-features in fused silica using focused-ion-beam	P-EIBL10	Agora
Stephen Gilmartin	Nanoscale Device Fabrication using the 2-Step NERIME Nanolithography Process	P-EIBL11	Agora
Enikő Horváth	Morphological and Electrical Study of FIB Deposited W Wires	P-EIBL12	Agora
Takayuki Yabe	CD and IP accuracy in Electron Beam Character Projection technology	P-EIBL13	Agora
Guido Piaszenski	Zero Stitching Error E-Beam Exposure for Next Generation Atom Chips	P-EIBL14	Agora
Ho Seob Kim	Low Voltage Imaging Detection Methods for Microcolumn System	P-EIBL15	Agora
José I. Martín	Large arrays of dots fabricated by Electron Beam Lithography	P-EIBL16	Agora

Posters

Maskless Lithography / Mask Technology			
Yong-Chae Chung	Theoretical Investigation of Pattern Printability of Oxidized Si and Ru Capping Model for Extreme Ultraviolet Lithography (EUVL)	P-ML/MK1	Agora
Yijian Chen	Wavefront Modulation to Suppress Image Blur for EUV Maskless Lithography	P-ML/MK2	Agora
Xiaowei Guo	Surface-plasmon polariton interference nanolithography	P-ML/MK3	Agora
Dong-Weon Lee	Micro/nanoheater-integrated cantilevers for micro/nano lithography applications	P-ML/MK4	Agora
Microsystems and their Fabrication			
yong chen	Hot strip devices for thermal characterisation of droplet size nanofluid samples	P-MST01	Agora
Daniela Andrijasevic	Aspects of micro structuring Low Temperature Cofired Ceramic (LTCC) for realisation complex 3D objects by embossing	P-MST02	Agora
Alexander Doll	Characterization of Active Silicon Microvalves with Piezoelectric Membrane Actuators	P-MST03	Agora
Mark Rosamond	Substrate independent fabrication of a non-planar probe card	P-MST04	Agora
Ioannis Raptis	Fabrication of conductometric chemical sensors with a novel lithographic method	P-MST05	Agora
Takao Matsumoto	A Microfabricated Boersch Phase Plate for Electron Microscopy	P-MST06	Agora
Maria Villarroya	Fabrication of nano-gaps for MEMS prototyping using Focused Ion Beam as a lithographic tool and Reactive Ion etching pattern transfer	P-MST07	Agora
Belen Solano	Design and testing of a Polymeric Microgripper for cell Manipulation	P-MST08	Agora
zhi ming Wang	Microfluidic Cooling of Semiconductor Light Emission Diodes	P-MST09	Agora
Natalia Balabanava	Effect of roughness on adhesion of polymeric coatings used for microgrippers	P-MST10	Agora
Stephan Keller	Optimized dry-release and passivation of thin SU-8 cantilevers	P-MST11	Agora
Beom-Hoan O	Fabrication of MMI Optical Power Splitter by UV Embossing with PDMS Mold	P-MST12	Agora
Francisco J. Blanco	Flexible and Biocompatible Polymer Microfluidic Devices with Integrated Electrodes Based on a CMOS Compatible Technology	P-MST13	Agora
Maria Nordström	Novel fabrication technique for free-hanging polymeric structures	P-MST14	Agora
Timo Mappes	X-Ray Lithography for Devices with High Aspect Ratio Polymer Submicron Structures	P-MST15	Agora
Walter Smetana	A multi-sensor biological monitoring module built up in LTCC-technology	P-MST16	Port Vell
Andrei Lucian Boglea	Advanced laser based tool for micro-assembly	P-MST17	Port Vell
keith houston	Novel micro-gripper coatings to reduce forces of adhesion during micromanipulation:	P-MST18	Port Vell
Philipp Nellen	Focused Ion Beam Modifications of Indium Phosphide Photonic Crystals	P-MST19	Port Vell
Roman Holly	Fabrication of silicon 3D taper structures for optical fibre to chip interface	P-MST20	Port Vell
Ko Chu-Jung	Manipulation of the phase separation of organic blends in sub-micron scale	P-MST21	Port Vell
Iwona Wyzkiewicz	Novel photoimageable process for fabrication of microfluidic structures	P-MST22	Port Vell
Philip Prewett	Micro-opto-electromechanical system for x-ray focusing	P-MST23	Port Vell
Marc Bendahan	New Ethanol Sensor Based on Organic Semiconductor Thin Film	P-MST24	Port Vell
xueyong wei	Fabrication of Ni-Al ₂ O ₃ Composite Microcomponent by Electroforming	P-MST25	Port Vell
Ivo W. Rangelow Ivo W. Ra	Piezoresistive and Self-Actuated 128-Cantilever Arrays for Nanotechnological Application	P-MST26	Port Vell
Søren Dohn	Cantilever readout by hard contact	P-MST27	Port Vell
adrien Plecis	Fabrication of complex and robust microfluidic devices based on glass-PDMS-glass technology	P-MST28	Port Vell
Ramona Mateiu	Reliability of Poly (3,4-Ethylenedioxiithiophene) Strain Gauge	P-MST29	Port Vell
Milan Držik	Thermomechanical response of membrane-like MEMS component	P-MST30	Port Vell
Rafal Wierzbicki	Concepts of force-feedback systems for direct micromanipulation.	P-MST31	Port Vell
Humberto Campanella	Process considerations in fabricating bulk acoustic wave resonators	P-MST32	Port Vell
Ioanna Giouroudi	A Force Feedback System for Micromanipulation with Stereoscopic Imaging.	P-MST33	Port Vell
Dong-Weon Lee	MEMS-based modular actuators for capsular endoscopy applications	P-MST34	Port Vell
Harutaka Mekaru	Development of ultrasonic micro hot embossing technology	P-MST35	Port Vell
Javier Rodriguez-Viejo	High Temperature Nanocalorimetry using membrane-based microreactors	P-MST36	Port Vell
Jose Antonio Plaza	Novel cantilever design with high control of the mechanical performance	P-MST37	Port Vell
Angeliki Tserepi	A novel process for irreversible bonding of PDMS and PMMA substrates	P-MST38	Port Vell
Elena Cianci	Young's modulus and residual stress of DF PECVD silicon nitride for MEMS free standing membranes	P-MST39	Port Vell
Marc Bendahan	WO ₃ Sensor Response According to Operating Temperature: Experiment and Modelling	P-MST40	Port Vell
Fu-Hsiang Ko	Fabrication of a Gas Sensor with a Piezoelectric PZT Film Deposited by a Novel Hydrothermal Microwave-Assisted Annealing	P-MST41	Port Vell
Luca Troisi	High resolution pixel definition in hybrid microcavities.	P-MST42	Port Vell
Mingqiang Bu	Design and FEM Simulation of a Microfluidic Magnetic Beads Separator	P-MST43	Port Vell
Christophe Serre	Optimization keys for vibrational electromagnetic generators	P-MST44	Port Vell
Javier Sesé	Process development for the fabrication of Microsystems using zeolites	P-MST45	Port Vell
Ana Sancho	3D macroporous structures for the development of high capacitance silicon integrated microcapacitors	P-MST46	Port Vell
Andrea Coppa	Building the CMUT for imaging applications from top to bottom	P-MST47	Port Vell
B. S. Kang	Fabrication and Characterization of a Pressure Sensor Using a Pitch-based Carbon Fiber	P-MST48	Port Vell
Marcin Juchniewicz	Novel technology for stamp fabrication	P-MST49	Port Vell
Ioanna Giouroudi	Test Device for Rotating Microsystems	P-MST50	Port Vell
Ilaria Inghrosso	Fabrication of AlN/Si SAW delay lines with very low RF signal noise	P-MST51	Port Vell
Nadja Adamovic	Development of UV-LIGA integrated vibrometer using 3x3 directional coupler	P-MST52	Port Vell
Fang-Chung Chen	Fabrication of a microlens array using ink-jet printing on a pre-patterned substrate by self-assembled monolayers	P-MST53	Port Vell
Burkhard Volland	Duo-action electrothermal microgripper	P-MST54	Port Vell
Stella Vallejos	Micro-machined WO ₃ -based sensors selective to oxidizing gases	P-MST55	Port Vell
Ken-ichiro Nakamatsu	Structure analysis of wire rod of nanosprings fabricated by FIB-CVD	P-MST56	Port Vell
Holger Götzte	Development of a micromanipulator based on piezoelectric-technology	P-MST57	Port Vell
Christos Tsamis	Pulsed mode operation of low power SnO ₂ sensors for improved gas selectivity	P-MST58	Port Vell
Carlos Molpecceres	Advanced 3D micromachining techniques using UV laser sources	P-MST59	Port Vell
Pablo Luis Pernas	Integrated electro-optic Mach-Zehnder modulator fabricated by vapour Zn-diffusion in LiNbO ₃	P-MST60	Port Vell

Posters

Nanodevices				
Florian Stade	Fabrication of metallic nanostructures for investigating plasmon-induced field enhancement	P-NDEV01	Port Vell	
Richard Langford	Magnetoresistance and Spin Diffusion in Multi-Wall Carbon Nanotubes	P-NDEV02	Port Vell	
Zsolt E. Horváth	Carbon Nanotube Mat Chemical Sensors	P-NDEV04	Port Vell	
Gemma Rius	Response of carbon nanotube transistors to electron beam exposure	P-NDEV05	Port Vell	
Zachary J. Davis	Nano-mechanical resonators for mass sensing applications	P-NDEV06	Port Vell	
Hong-Bay Chung	Characteristic improvement of Ge ₁ Se ₁ Te ₂ phase change memory	P-NDEV07	Port Vell	
Somsak Panyakeow	Self-Assembled Quantum Dot Molecules for Practical Nanostructure Devices: Bottom-Up Approach	P-NDEV08	Port Vell	
Seung-Beck Lee	Fabrication of Flexible and Transparent Single Wall Carbon Nanotube Gas Sensors by Selective Vacuum Filtration and Poly(dimethyl siloxane) Mold Transfer	P-NDEV09	Port Vell	
Lisa Creswell	Spin resonance response of silicon-on-insulator single electron transistors	P-NDEV10	Port Vell	
Montserrat Nafria	Analysis of the degradation of Hf/SiO ₂ gate stacks using nanoscale and device level techniques.	P-NDEV11	Port Vell	
Sangsig Kim	A fabrication technique of top-gate nanowire FETs by a photolithography process	P-NDEV12	Port Vell	
M.J. Chen	Metal-Insulator-Semiconductor Light-Emitting Diodes with Ultrathin Al ₂ O ₃ Layer Grown by Atomic Layer Deposition on Silicon	P-NDEV13	Port Vell	
Sangsig Kim	Memory Characteristics of Al Nanocrystals Embedded in Al ₂ O ₃ Layers	P-NDEV14	Port Vell	
Hideo Sunami	Plasma-Doping Induced Damages Associated with Source/Drain Formation in Beam-Channel MOS Transistor on 1- μ m Thick SOI Substrate	P-NDEV15	Port Vell	
Stephan Abermann	Processing and evaluation of metal gate/high-k/Si capacitors	P-NDEV16	Port Vell	
Yijian Chen	Double Surrounding-Gate Control of Si Body in Vertical Integrated-Gate CMOS	P-NDEV17	Port Vell	
Zoran Djuric	Thermomechanical Noise of Nanooscillators with Time-Dependent Mass	P-NDEV18	Port Vell	
Sangsig Kim	Fabrication of Thin-film Transistors Based on CdTe/CdHgTe Nanocrystals	P-NDEV19	Port Vell	
Ko Chu-Jung	Microwave annealing processes in organic photovoltaic devices	P-NDEV20	Port Vell	
Ming Liu	Fabrication of SOI based nano-scale mechanical resonator coupled with a single electron transistor	P-NDEV21	Port Vell	
Hong-Bay Chung	Investigation of Resistance Change Characteristics with Applied Electric Field on Ag / Chalcogenide As ₂ S ₃ and As ₄₀ Ge ₁₀ Se ₁₅ S ₃₅ Thin Film Structure	P-NDEV22	Port Vell	
Han-geon Kim	2D Quantum Mechanical Device Modeling and Simulation: FinFET Having an Isolated n+/p+ Gate Region Strapped with Metal and Poly-silicon	P-NDEV23	Port Vell	
JOSE MARIA DE TERESA	Transport properties of Fe ₃ O ₄ thin films for applications in Spin Electronics	P-NDEV24	Port Vell	
Jose Calderon-Moreno	Silver Nanoprism Coatings on Optical Glass Substrates.	P-NDEV25	Port Vell	
Nanoimprint Lithography				
Nicolas Chaix	Nanoimprinting lithography on 200 mm wafers for optical applications	P-NIL01	Agora	
Douglas Resnick	Template Replication for Full Wafer Imprint Lithography	P-NIL02	Agora	
Filip Crnogorac	Nano-Graphoepitaxy of Semiconductors for 3D Integration	P-NIL03	Agora	
Rasmus Haugstrup Pedersen	Fabrication of Long-Range Surface Plasmon Polariton Devices by Nanoimprint Lithography	P-NIL04	Agora	
Ki-don Kim	Replication of UV-NIL Stamp Using Fluorine Doped DLC Coating	P-NIL05	Agora	
Namil Koo	Improved mold fabrication for the definition of high quality nanopattern by Soft UV Nanoimprint lithography using diluted PDMS material	P-NIL06	Agora	
W. Lee	Fabrication of wafer-scale Ni imprint stamps based on interference lithography and their applications for perfectly ordered anodic alumina membranes	P-NIL07	Agora	
Yoshihiko Hirai	Low cost and rapid reproduction of fine structures by nano casting lithography	P-NIL08	Agora	
Jun Taniguchi	Fabrication and resolution evaluation of three-dimensional nanoimprint mould using inorganic resist in low acceleration voltage electron beam lithography	P-NIL09	Agora	
Pauline Voisin	High-resolution fused silica mold fabrication for UV-Nanoimprint	P-NIL10	Agora	
Masaaki Yasuda	Analysis of yield stress of crystalline and amorphous Si mold in nanoimprint	P-NIL11	Agora	
Nikolaos Kehagias	Reverse UV Nanoimprint Lithography technique for 3D nanofabrication	P-NIL12	Agora	
Michael Muehberger	A Moiré Method for High Accuracy Alignment in Nanoimprint Lithography	P-NIL13	Agora	
Tanguy LEVEDER	Resist viscosity measurement for accurate nano-imprint simulation	P-NIL14	Agora	
Helmut Schiff	Fast heating and cooling in nanoimprint using an alignment fixture	P-NIL15	Agora	
Michael Häfner	Simple High Resolution Nanoimprint-Lithography	P-NIL16	Port Vell	
Stefan Landis	Investigation of capillary bridges growth in NIL process	P-NIL17	Port Vell	
Guido Plaszenski	3-D Structures for UV-NIL Template Fabrication with Greyscale E-Beam Lithography	P-NIL18	Port Vell	
Sergey Zaitsev	Design, fabrication and testing of rheological nano-indenter.	P-NIL19	Port Vell	
Hella-Christin Scheer	Fingerprint stamp for evaluation of polymer flow time constants in thermal nanoimprint	P-NIL20	Port Vell	
Tanguy LEVEDER	Post demolding pattern reflow in hot-embossing lithography	P-NIL21	Port Vell	
Santos Merino	The use of automatic demolding on Nanoimprint Lithography processes	P-NIL22	Port Vell	
JaeJong Lee	The UV-Nanoimprint Lithography Equipment with Multi-head Imprinting Unit for Sub-50nm Half-pitch Patterns	P-NIL23	Port Vell	
Pauline Voisin	High sensitive and etch-resistant material for UV-Nanoimprint	P-NIL24	Port Vell	
Yasuhide Kawaguchi	Fluorinated materials for UV Nanoimprint Lithography	P-NIL25	Port Vell	
Seunghyun Ra	Fine patterning of thermoset resins for PCB using thermal imprint technology	P-NIL26	Port Vell	
Heon Lee	Improving nickel stamp fabrication with hot embossing and electroforming	P-NIL27	Port Vell	
Ken-ichiro Nakamatsu	Fluorinated diamond-like carbon coating as an anti-sticking layer on a nanoimprint mold	P-NIL28	Port Vell	
Thorsten Wahlbrink	Dimensional stability in step & repeat UV-nanoimprint lithography	P-NIL29	Port Vell	
Joachim Zajadacz	Flexible fabrication of 3d structures with UV curable acrylates and cycloaliphatic epoxides	P-NIL30	Port Vell	
Marko Vogler	Development of a novel, low-viscosity UV-curable polymer system for UV nanoimprint lithography	P-NIL31	Port Vell	
Tony DiBiase	Defect characterization of Nano Imprint templates including cleaning process and defect densities at both template and wafer levels	P-NIL32	Port Vell	
Alexei L. Bogdanov	Optimized Process for S-FIL Template Fabrication at sub-70 nm scale	P-NIL33	Port Vell	
Beom-Hoan O	Fabrication of a Polymeric Photonic Crystal Wavelength-splitter Using UV-embossing Technology	P-NIL34	Port Vell	
Masaaki Kurihara	3D structural templates for UV-NIL fabricated with gray-scale lithography	P-NIL35	Port Vell	
Tomi Haatainen	Stamp replication by Step&Stamp Imprint Lithography	P-NIL36	Port Vell	
Heon Lee	Thermal imprinting lithography process using sub-micron sized nickel template	P-NIL37	Port Vell	
Saskia Möllenbeck	Investigation of the separation of 3D-structures with undercuts	P-NIL38	Port Vell	

Posters

Nanoscale Engineering and Fabrication				
Wuxia Li	Fabrication and characterisation of self-assembled nanomagnets by electrodeposition based on anodic aluminium oxide templates	P-NSC01	Agora	
Ran Ji	Kill two birds with one stone: Templated fabrication of nanowire and nanoring arrays based on interference lithography and electrochemical deposition	P-NSC02	Agora	
Christoph Schoendorfer	FIB induced growth of antimony nanowires	P-NSC03	Agora	
Matthias Schramboeck	In-based Quantum Dots on Al _x Ga _{1-x} As Surfaces	P-NSC04	Agora	
E Kondoh	Nanostructure Formation using Supercritical Carbon Dioxide Fluids	P-NSC05	Agora	
Reo Kometani	Nano-factory with the integrated manipulation system having the 3-D fingers fabricated by focused-ion-beam chemical-vapor-deposition	P-NSC06	Agora	
Michael Zier	Ultra-shallow pn-junction fabrication for piezoresistive AFM deflection sensors	P-NSC07	Agora	
Fredrik Persson	Investigation of fluid dynamics during capillary filling in high aspect ratio SiO ₂ nanochannels	P-NSC08	Agora	
Christoph Deneke	InGaAs/GaAs-alkanethiolate radial superlattices	P-NSC09	Agora	
Bob van Someren	Growth of a Carbon Nanotube on a Tungsten Tip using Electron Beam Induced Deposited Iron Catalyst	P-NSC10	Agora	
Daryl Beggs	Design and fabrication of high-efficiency fibre couplers for nanophotonic devices	P-NSC11	Agora	
Massimo De Vittorio	Fabrication of force sensors based on two-dimensional photonic crystal technology	P-NSC12	Agora	
Seung-Beck Lee	Template assisted electrostatic assembly of colloidal Au nanoparticles	P-NSC13	Agora	
William Arora	Membrane folding by ion implantation stress for 3-D nanomanufacturing	P-NSC14	Agora	
Hsuen-Li Chen	Fabrication of three-dimensional inverse-opal structures with tunable photonic bandgaps by utilizing polymer and silica hybrid colloids	P-NSC15	Agora	
David Peyrade	Real-time imaging of dielectrophoresis integration of gold colloids into NIL devices	P-NSC16	Port Vell	
Lothar Bischoff	Defect induced nanowire growth by FIB implantation	P-NSC17	Port Vell	
Liam O'Faolain	Shot-Shifting for Nanophotonic Applications	P-NSC18	Port Vell	
Irene Fernández-Cuesta	Fabrication of interdigitated nanoelectrodes by a combination of AFM local anodic oxidation and nanoimprint lithography	P-NSC19	Port Vell	
Konstantins Jefimovs	Fabrication of Fresnel zone plates for hard X-rays	P-NSC20	Port Vell	
Minoru Obara	Plasmonics mediated nanohole fabrication by femtosecond laser	P-NSC21	Port Vell	
Yong chen	Assembling of Nanoparticles on Patterned Micro and Nano Surfaces	P-NSC22	Port Vell	
Angeliki Tserepi	Nanostructuring of PDMS surfaces: Dependence on casting solvents	P-NSC23	Port Vell	
Masaaki Yasuda	Beam Condition Dependence of Electron Irradiation Damages in Carbon Nanotubes	P-NSC24	Port Vell	
Ran Ji	Fabrication of wafer-scale arrays of silicon nanofins and silica nanochannels based on interference lithography and oxidation size-reduction strategy	P-NSC25	Port Vell	
Annamaria Gerardino	Fabrication and characterization of point defect photonic crystal nanocavities for	P-NSC26	Port Vell	
Jean Lapointe	Fabrication of devices based on site-selective growth of self-assembled InAs/InP quantum dots	P-NSC27	Port Vell	
Y. F. Mei	Semiconductor nanochannel networks by deterministic layer wrinkling	P-NSC28	Port Vell	
Minoru Obara	Nano-void array in dielectric materials by femtosecond laser	P-NSC29	Port Vell	
Neal Meyer	SEM Verification of nDSE (nano Displacement Sensing & Estimation)	P-NSC30	Port Vell	
Klaus Kallis	Lithography Independent High Accuracy Fabrication and Characterization of Next Generation Nano-MOS-Transistors with L=25 nm and W=75 nm	P-NSC32	Port Vell	
Antonio Quattieri	Colloidal nanocrystal air bridge fabricated by direct lithography	P-NSC33	Port Vell	
Hayato Sone	Growth control of self-assembled ErSi ₂ nanowire on silicon surface	P-NSC34	Port Vell	
Ryouki Watanabe	Atomic structure analysis of self-assembled ErSi ₂ nanowires formed on Si substrates	P-NSC35	Port Vell	
Yifang Chen	Fabrication of ferromagnetic nanoconstrictions by electron beam lithography using LOR/PMMA bilayer technique	P-NSC36	Port Vell	
Moonsuk Yi	Enhanced Performance of OTFT by Ar ion treatment onto gate dielectric	P-NSC37	Port Vell	
Jun-ichi Fujita	Graphitic Tube Transformation of FIB-CVD Pillar by Joule Heating with Flash Discharge	P-NSC38	Port Vell	
In-Sung Park	Nanoscale patterning using photo-assisted polymer transfer lithography	P-NSC39	Port Vell	
Alexander Prinz	Fabrication of GaAs/InGaAs nanoshells using AFM lithography.	P-NSC40	Port Vell	
Muhammad Rafiq	Fabrication of vertical nanopillar devices	P-NSC41	Port Vell	
John Dyreby	Simulating Fluid Flow and Capillary Interactions in Lithographically Directed, Evaporation Driven Self-Assembly Systems	P-NSC42	Port Vell	
Sachin Sonkusale	Uniformity analysis of array of sub-25 nm linewidth structures and Palladium nanowires obtain by PEDAL process	P-NSC43	Port Vell	
Christos Christides	Effect of magnetic-field on metal-insulator transitions in Bi wire structures	P-NSC44	Port Vell	
Dong Sung Kim	Fabrication of microchannel with nanopillar array using micromachined AAO	P-NSC45	Port Vell	
Jongheop Yi	Fabrication of mesa-type electrodes via AFM oxidation for Pt ion detection	P-NSC46	Port Vell	
Akinori Ozasa	Annealing Effect of Electronic Properties for Wires Fabricated by FIB and EB-CVD	P-NSC47	Port Vell	
Filippo Romanato	Fabrication by X-ray Lithography and Electrodeposition of 2D and 3D CdSe Photonic Crystal	P-NSC48	Port Vell	
Thanassis Spiliotis	Exchange Bias in Ferromagnetic – Antiferromagnetic submicron structures	P-NSC49	Port Vell	
Hans Mulders	Measurements and calculations of FIB milling yield of bulk metals	P-NSC50	Port Vell	
Kwan-Sun Yoon	First-principles Investigation with the Classical Rate Theory on Prefactor of Indium in Silicon	P-NSC51	Port Vell	
Bo Cui	Fabrication of nanoring array by nanoimprint lithography and reactive ion etching	P-NSC52	Port Vell	
Somchai Ratanathammapha	In-droplet-induced formation of InP nanostructures by solid-source molecular-beam epitaxy	P-NSC53	Port Vell	
Valentinas Snitka	Functionalized porphyrin nanotubes produced by ionic self-assembly	P-NSC54	Port Vell	
Heon Lee	Selective deposition of the silver nano particles using patterned the hydrophobic Self-Assembled Monolayer patterns and zero-residual Nano imprint Lithography	P-NSC55	Port Vell	
Giovanni Pennelli	Advantages of an almost triangular cross section for silicon nanostructure fabrication on SOI substrates	P-NSC56	Port Vell	
Joong-Sik Kim	Atomistic Modeling for Understanding the Suppression of Boron Diffusion in Ge Pre-amorphized Silicon Substrate	P-NSC57	Port Vell	
Cho Cho Thet Cho Cho The	Growth of Long-Range, Ordered InAs Quantum Dots on InGaAs/GaAs Cross-Hatch Virtual Substrate	P-NSC58	Port Vell	
Neal Meyer	Three Beam Nanoscale Prototyping for Photonics	P-NSC59	Port Vell	
Changzhi Gu	A Flexible Method for Fabricating Ion-beam Sculpting Nanopore	P-NSC60	Port Vell	
Pattern Transfer				
Jose Antonio Plaza	DRIE based novel technique for AFM probes fabrication	P-PAT1	Agora	
Magnus Lindblom	SU-8 mold for high-aspect-ratio nickel zone plates	P-PAT2	Agora	
Hiroaki Kawata	Fabrication of Si mold with smooth side wall by new plasma etching process	P-PAT3	Agora	
Maryna Lishchynska	Modelling pattern transfer in stencil lithography	P-PAT4	Agora	
Chan Woo Park	Reverse nanostencil lithography using dual pattern transfer	P-PAT5	Agora	
Zheng Cui	Fabrication of Meta-materials by Lift-off Using PMMA/Al Stack	P-PAT6	Agora	
Dimitris Davazoglou	Copper metallization based on direct liquid injection hot-wire CVD	P-PAT7	Agora	
Eugenio Sillero	Selective etching of AlInN/GaN heterostructures for MEMS technology	P-PAT8	Agora	

Posters

Photon Lithography				
Roxann Engelstad	Assessing Particle-Induced Distortions during Wafer Chucking	P-PHO01	Agora	
Jonathan Jeauneau	Materials and Performance of Multi-layer Lithography Schemes	P-PHO02	Agora	
Chun-Hung Lin	Influence of mask magnification factor on the diffracted light in extreme ultraviolet lithography	P-PHO03	Agora	
Fu-Der Lai	The 32, 45 and 65 nm-technology-node ArF-line high transmittance attenuated phase shift mask blank using monolayer amorphous Al ₂ O ₃ -TiO ₂ composite films	P-PHO04	Agora	
Mario Marconi	Development of a table top Nanopatterning tool with Extreme Ultraviolet laser illumination	P-PHO05	Agora	
Jianliang Li	Improvement of Model Kernel Representation in Process Simulation by Taking Pattern Correlation into account	P-PHO06	Agora	
Philip Prewett	Embedded Metal Mask Enhanced Evanescent Near Field Optical Lithography	P-PHO07	Agora	
Balint Meliorisz	Simulation of proximity and contact lithography	P-PHO08	Agora	
Gerhard Kalkowski	Flatness Characterisation Techniques for EUV Mask Chucks	P-PHO09	Agora	
amandine borjon	Analysis of the diffraction patterns for optimal Assist Feature placement.	P-PHO10	Agora	
Arjan Verhappen	Polarized Illuminator Impact on Line Edge Roughness	P-PHO11	Agora	
Hsuen-Li Chen	Fabrication of sub-wavelength antireflective structures in solar cells by utilizing modified illumination and defocus techniques in optical lithography	P-PHO12	Agora	
Sungsoo Suh	Binary mask side lobe suppression using space scattering bar	P-PHO13	Agora	
Dryver Huston	Debris Mitigation Strategies for Laser Copper Plasma X-ray Sources	P-PHO14	Agora	
Atsunobu Une	Nano Contact with a Vacuum Pin Chuck around the Periphery of a Wafer	P-PHO15	Agora	
Sang-Kon Kim	Thermal Mechanism for Optical Proximity Correction	P-PHO16	Agora	
Christian Gardin	Etch modelling for MB-OPC for 65nm node	P-PHO17	Agora	
Resist and Resist Processing				
George Patsis	Stochastic simulation studies of molecular resists	P-RES01	Agora	
Alex Robinson	Suppression of Pinhole Defects in Fullerene Molecular Electron Beam Resists	P-RES02	Agora	
Jun Taniguchi	Improving sensitivity and resolution in inorganic positive EB resist	P-RES03	Agora	
Anja Voigt	Improved properties of hybrid epoxy nanocomposites for specific applications in the field of MEMS/ NEMS	P-RES04	Agora	
Sergey Zaitsev	Fast electron resist contrast definition by "fitting before measurement" approach.	P-RES05	Agora	
Daiju Shiono	LER evaluation of molecular resist for EUV lithography	P-RES06	Agora	
Maria Chiara Ubaldi	Molecular roughness analysis of developed resist by LER method	P-RES07	Agora	
Beom-Hoan O	Fabrication of Vertical Optical Interconnecting Structure using Photoresist Reflowed Mold Structures	P-RES08	Agora	
Juan Schneider	Linear Coating for Monolayer and Ultra Thin Film Production	P-RES09	Agora	
Cristina Martin	Electron beam lithography at 10 keV using an epoxy based high resolution negative resist	P-RES10	Agora	
Tang Xiongui	Simulation and analysis for microstructure profile of optical lithography based on SU-8 thick resist	P-RES11	Agora	
Katerina Tsougeni	Photosensitive PDMS materials for Optical Lithography	P-RES12	Agora	
Haifang Yang	Comparative Study of E-beam Resist Processes at Different Development Temperatures	P-RES13	Agora	
Svetlana Bystrova	Study of crack formation in high-aspect ratio SU-8 structures on silicon	P-RES14	Agora	
Abellán Marián	EBL Bi-layer resist scheme for CdTe submicron structures for lift-off processing	P-RES15	Agora	
RF-MEMS. NEMS				
Alvaro San Paulo	Acoustic wave field imaging by atomic force microscopy in RF MEMS resonators: New methods and applications	P-RF01	Port Vell	
Carlos Calaza	Electromechanical Characterization of low actuation voltage RFMEMS capacitive switches based on DC CV measurements	P-RF02	Port Vell	
Kazuaki Tanaka	Parasitic Effect on MEMS Resonator Model Parameters	P-RF03	Port Vell	
Irina Khmyrova	Equivalent circuit modeling of resonant cantilever-floating gate HEMT	P-RF04	Port Vell	
Alexander Mehdaoui	Vertical co-integration of AlSi MEMS tunable capacitors and Cu inductors for tunable LC blocks	P-RF05	Port Vell	
arantxa uranga	Electrical detection of multiple resonant modes in a CMOS-MEMS cantilever	P-RF06	Port Vell	
Francesc Torres	Bulk Acoustic Mode RF-MEMS Resonator Made From EBL and RIE Techniques	P-RF07	Port Vell	
Fu-Der Lai	The GHz surface acoustic wave filters fabricated by using an alternating phase-shifting mask design method and a mold with 5mm linewidth patterns	P-RF08	Port Vell	
Francesc Torres	Nanometer Scale Gaps for Capacitive Transduction Improvement on RF-MEMS Resonators	P-RF09	Port Vell	
ILKWON OH	Resonant Frequency and Instability of Multi-layered Micro-Resonators with Initial Imperfection Subject to Piezoelectric Loads	P-RF10	Port Vell	
Jon Ander Etxeberria Intxausti	Tunable MEMS Volume Capacitors for High Voltage applications	P-RF11	Port Vell	
Sofiane Soulimane	Planarization of photoresist sacrificial layer for MEMS fabrication	P-RF12	Port Vell	
Elena Cianci	Fabrication of RF MEMS switches on alumina wafers using PECVD a-Si as sacrificial layer	P-RF13	Port Vell	